



JPV

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Group Art Unit: 2823

VON AMMON ET AL.

Examiner: Jarrett J. Stark

Serial No.: 10/809,070

Filed: March 25, 2004

For: METHOD AND DEVICE FOR THE PRODUCTION OF A
SILICON SINGLE CRYSTAL SILICON SINGLE CRYSTAL,
AND SILICON SEMICONDUCTOR WAFERS WITH
DETERMINED DEFECT DISTRIBUTIONS

Attorney Docket No.: WSAG 0143 PUS

AMENDMENT UNDER 37 C.F.R. § 1.111

Mail Stop Amendment
Commissioner for Patents
U.S. Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action dated April 13, 2006, kindly amend the above-identified application as follows:

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8 (FIRST CLASS MAIL)

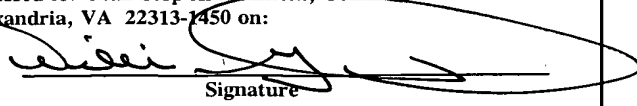
I hereby certify that this paper, including all enclosures referred to herein, is being deposited with the United States Postal Service as first-class mail, postage pre-paid, in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450 on:

May 9, 2006

Date of Deposit

William G. Conger

Name of Person Signing



Signature